

GasPro™ TEM-4000

Ultra-High Purity All 316L
In-Line Filter



GasPro™ TEM-4000 series filters are designed for 3nm particle retention at flow rates up to 200 slpm and temperatures up to 200°C.

Designed specifically for the semiconductor plasma ashing market. The all 316L SS welded filter offers a large surface area for the challenging high particulate asher process. This allows the tool owner to extend filter change out intervals and improves tool uptime & throughput.

Standard semiconductor industry fittings are offered for easy installation.

Specifications

- **Filtration rating**
Efficient 3 nm particle retention.
- **Maximum operating temperature**
200°C (392°F) in inert gas.
- **Maximum operating pressure**
20°C (68°F) 250 PSI.

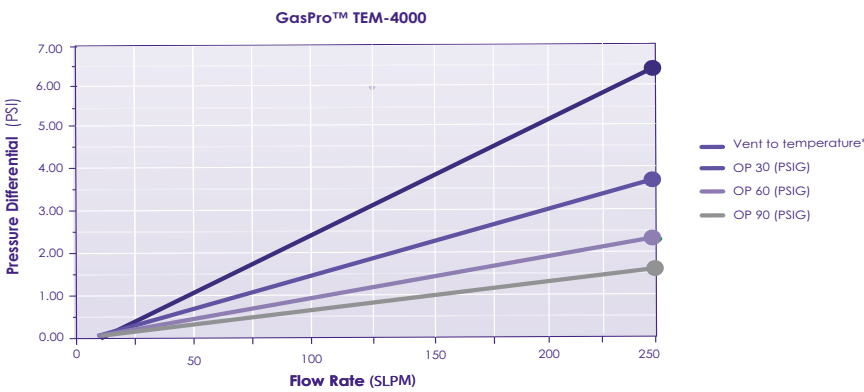
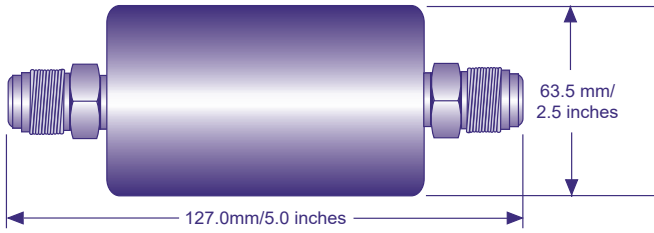
Typical Applications

- Semiconductor equipment point of use filter.

Features and Benefits

- **Construction**
All 316L stainless steel sintered fibre media and hardware.
- **Electro-polished housing**
The filter assemblies have a 15Ra electro-polished 316L stainless steel housing to prevent corrosion and particle build-up on interior surfaces.
- **Out of package cleanliness**
Our GasPro™ TEM-4000 filters are cleaned and packaged in a cleanroom with organic free handling for out-of-package, particle free, and chemical free cleanliness. Final assembly is purged with filtered nitrogen for initial cleanliness. Additional preconditioning is optional.
- **100% helium leak tested**
All units tested to 1×10^{-9} atm cc/second.

Specifications



* Operating pressure is the pressure necessary to achieve the flow rate for a product venting to 13.5 PSIA; dP=OP

TEM-4000 Part Numbers and Ordering Information

Part number	Description*	Filter media / housing	Filter housing OD	Length (L)
TEM-4015-8	1/2" M/M face seal	316 55	2.5"	127mm (5.00")

Other fittings available on request